



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Yukio MORISHIGE, *et al.*

Appln. No.: 09/989,162

Group Art Unit: 1763

Confirmation No.: 9610

Examiner: Sylvia R. MACARTHUR

Filed: November 21, 2001

Attorney Docket No.: Q67394

For: THIN FILM FORMING EQUIPMENT AND METHOD

AMENDMENT UNDER 37 C.F.R. § 1.111

MAIL STOP NON-FEE AMENDMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed April 4, 2003, please amend the above-identified application as follows:

IN THE CLAIMS:

Please cancel claims 10 and 12 without prejudice or disclaimer.

Please enter the following amended claims:

9. A method for forming a thin film on a substrate by decomposing gas introduced to a surface of a substrate held by a substrate holding device having a cover body which is disposed in an area surrounding said substrate held by said substrate holding device, said cover body being able to open and close by rotational movement, said method comprising:

a step of preventing said gas introduced to said surface of said substrate from being influenced by outside air,

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